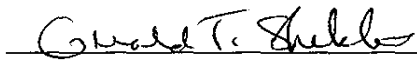




PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re U.S. Patent Application)	Art Unit: 1765
)	
Applicants: Satoshi Komiya et al.)	Confirmation No.: 2326
)	
Serial No.: 10/049,875)	<i>I hereby certify that this correspondence</i>
)	<i>is being deposited with the United</i>
Filed: February 12, 2002)	<i>Postal Service as first class mail in an</i>
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For: SILICON WAFER AND)	<i>FEE AMENDMENT / Commissioner for</i>
METHOD FOR)	<i>Patents / P.O. Box 1450 / Arlington,</i>
MANUFACTURE THEREOF,)	<i>Virginia 22313-1450</i>
AND METHOD OF)	
EVALUATION OF SILICON)	
WAFER)	
)	Gerald T. Shekleton Reg. No. 27,466
Examiner: Robert M. Kunemund)	

AMENDMENT

MAIL STOP FEE AMENDMENT
Commissioner for Patents
P.O. Box 1450
Arlington, Virginia 22313-1450

Sir:

The Office Action of June 3, 2003 has been carefully reviewed and the following amendment and remarks are made in response thereto.